Degradation of the aluminum filters on SDO/EVE

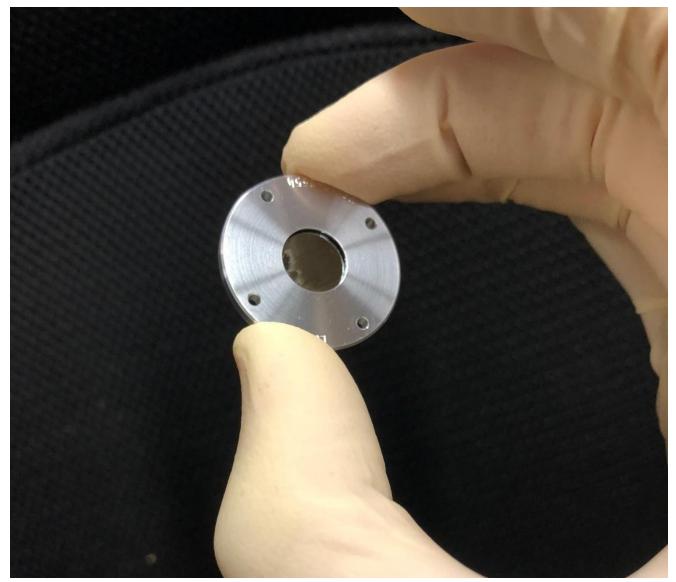
Bobby Berg

with Charlie Tarrio and Tom Lucatorto NIST

and Frank Eparvier, Andrew Jones Laboratory for Atmospheric and Space Physics University of Colorado

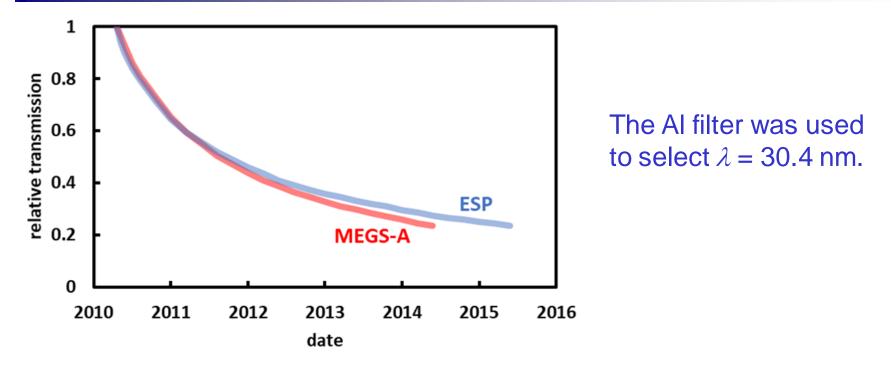
> SDO/EVE Science Team meeting 26 July 2023

Problem: Degradation of the aluminum filter



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Problem: Degradation of the aluminum filter



Q: How do we know the degradation occurred?

A1: Compared the primary filter to a reference filter with less exposure.

A2: Compared an SDO observation to one made with a sounding rocket.

Q: Why is this a problem?

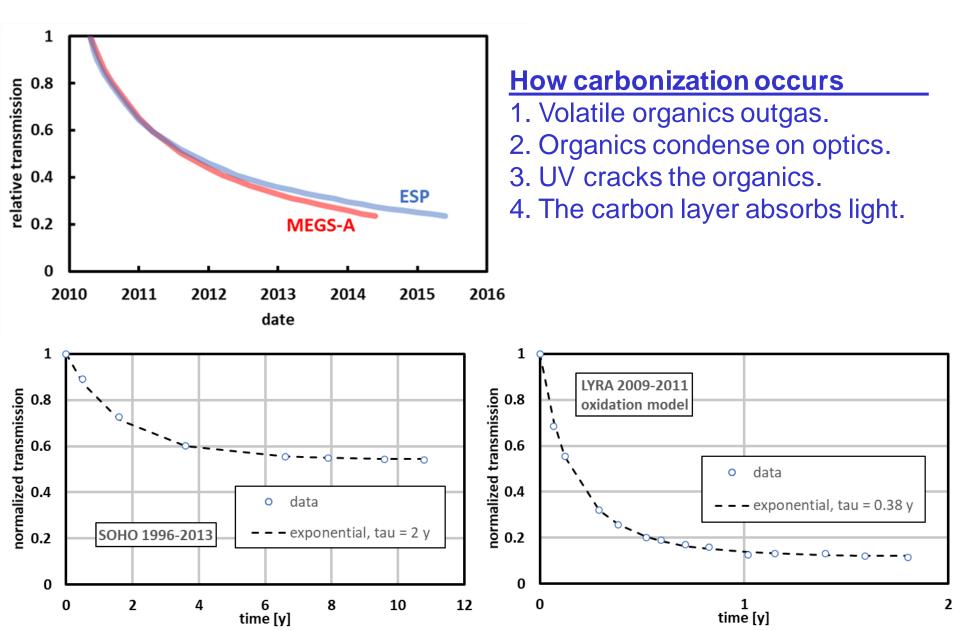
A: Increased uncertainty, cost of recalibration by sounding rocket flights.

Q: What caused it?

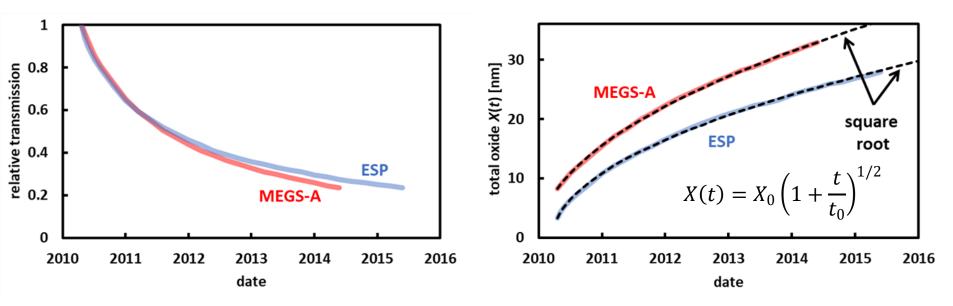
A: Carbon is the usual cause.



The usual suspect: Carbon



The degradation on SDO was different



The satellite materials were chosen to minimize outgassing of organics.

A nearby zirconium filter did not degrade.

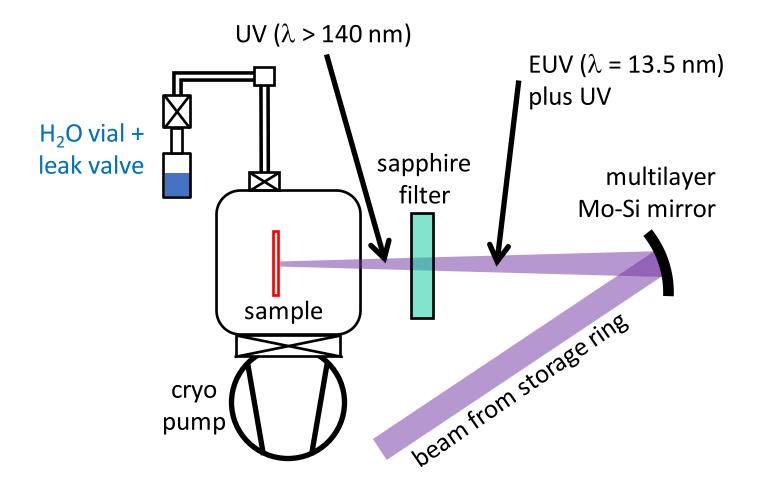
The time dependence was square root, $t^{1/2}$, not exponential, $e^{-t/\tau}$.

Aluminum oxide (Al_2O_3) can explain the degradation as well as carbon.

Water outgassing is always present, and AI + $H_2O \rightarrow AI_2O_3$.

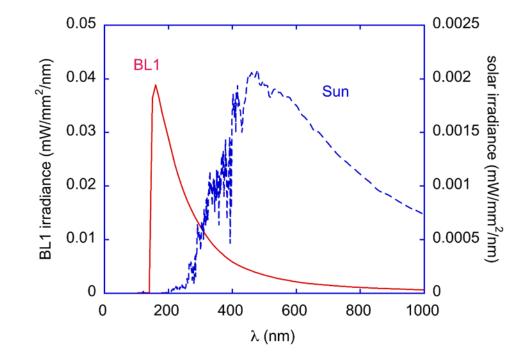


SURF (synchrotron) Beamline 1a





SURF (synchrotron) Beamline 1a





Three challenges

What: Demonstrate that carbonization did not cause the SDO problem.
Why: Carbon has been the usual cause for degraded UV optics.
How: Expose AI samples to SURF in an atmosphere of 10⁻⁶ Torr toluene.

What: Demonstrate the possibility of UV-induced oxidation.

Why: 24 nm of Al oxide has never been grown at 300 K and low pressure. How: Expose Al samples to SURF in a "humid" (10⁻⁶ Torr) atmosphere.

What: Model UV-induced oxidation

- Why: Allow accurate comparison between SURF results and SDO data.
- How: Combine photoemission, electron scattering, and oxidation.



SURF exposures and measurements of the oxide

Modeling the oxide growth

Comparing the model to the measurements

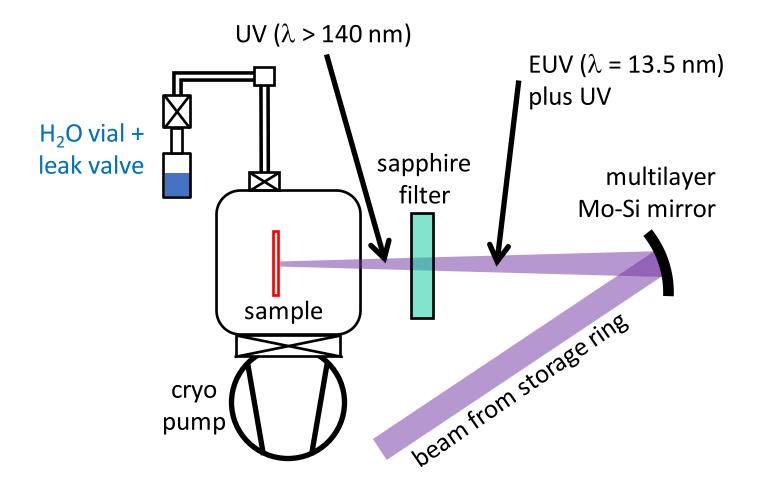
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SURF exposures and measurements of the oxide

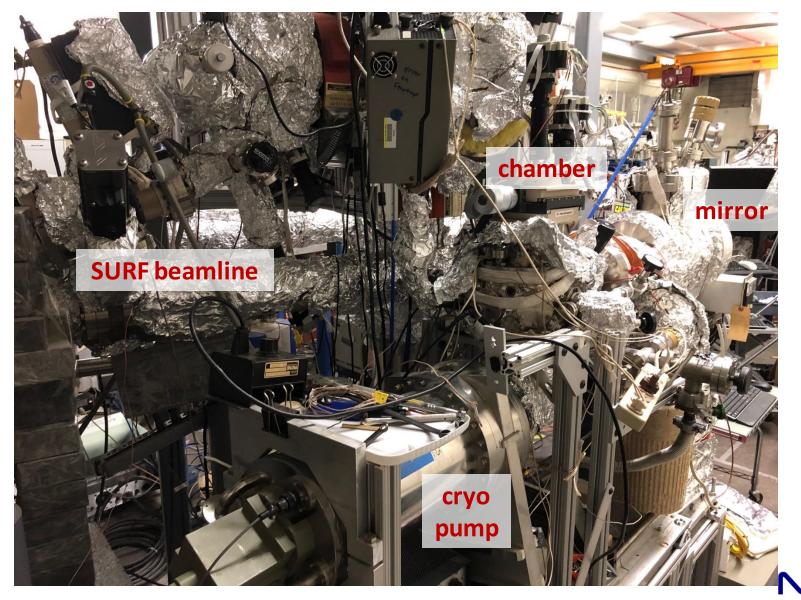


SURF (synchrotron) Beamline 1a





SURF beamline 1a



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SURF exposures: Knobs we can turn

	min	max	note
UV dose	40 J	3600 J	260 J/day x two weeks
average UV power	0.3 mW	3 mW	
UV cutoff	145 nm 8.6 eV	165 nm 7.5 eV	$AI - AI_2O_3$ work function = 2.6 eV
H ₂ O pressure	10 ⁻⁸ Torr	10 ⁻⁴ Torr	minimum is chamber outgassing



SURF exposures: Measure the oxide thickness



SURF beamline 7 Transmission of EUV (λ = 34 nm) is attenuated by oxygen.



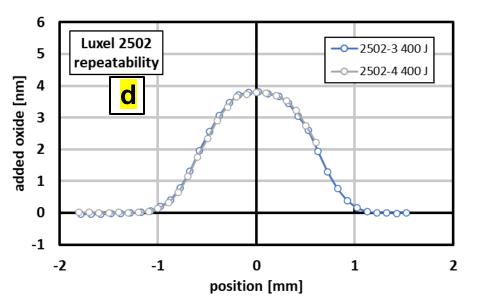
Reproducibility $\approx \pm 10\%$

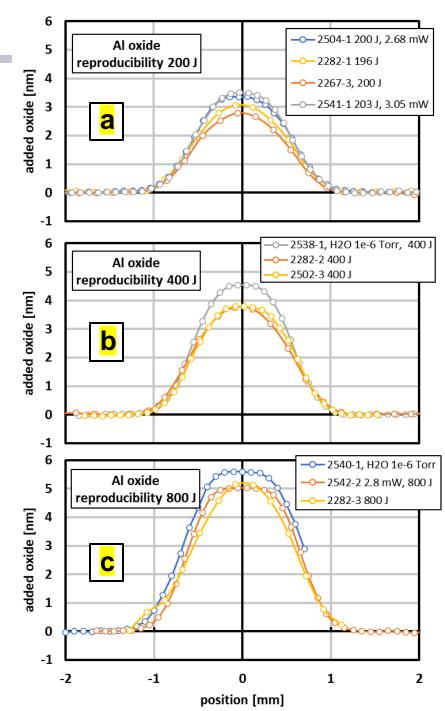
<u>Reproducibility</u> compares spots exposed on <u>different</u> filters with the same pressure and dose.

Repeatability compares spots on the same filter.

- **a**: Peak reproduced to about ±10%.
- **b**: Peak reproduced to about ±10%.
- c: Shape as well as the amplitude can vary.

d: Repeatability is about $\pm 1\%$.





Modeling the oxide growth

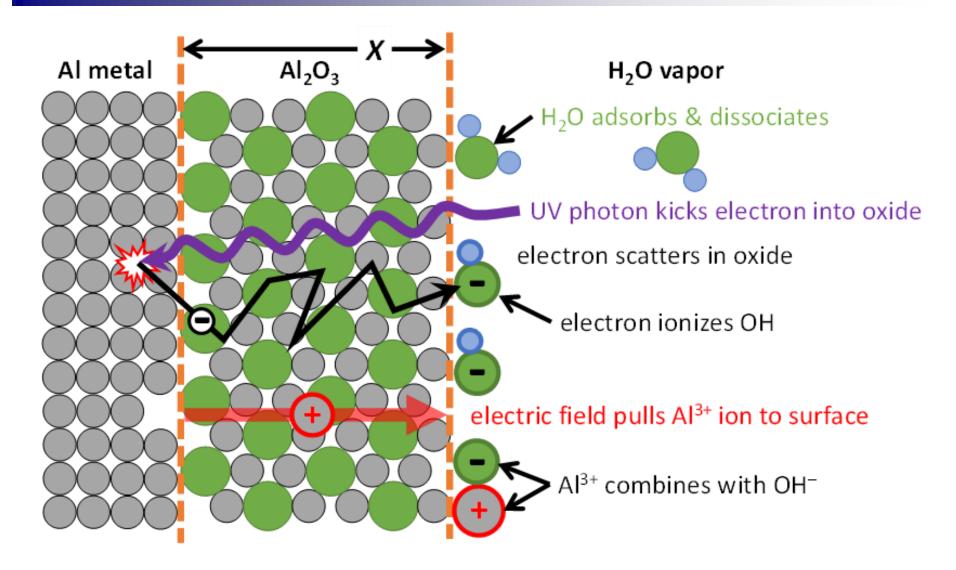


The five stages of UV-induced oxidation

- 1. UV photons kicks electrons from the metal into the oxide.
- 2. The electrons scatter in the oxide. Some reach the oxide-vacuum surface.
- 3. Electrons at the surface react with adsorbed H_2O to create OH^2 ions.
- 4. The OH⁻ ions create a field that pulls Al⁺³ ions to the oxide-vacuum surface.
- 5. The AI⁺³ and OH⁻ ions combine and create AI_2O_3 .



Concepts in the model



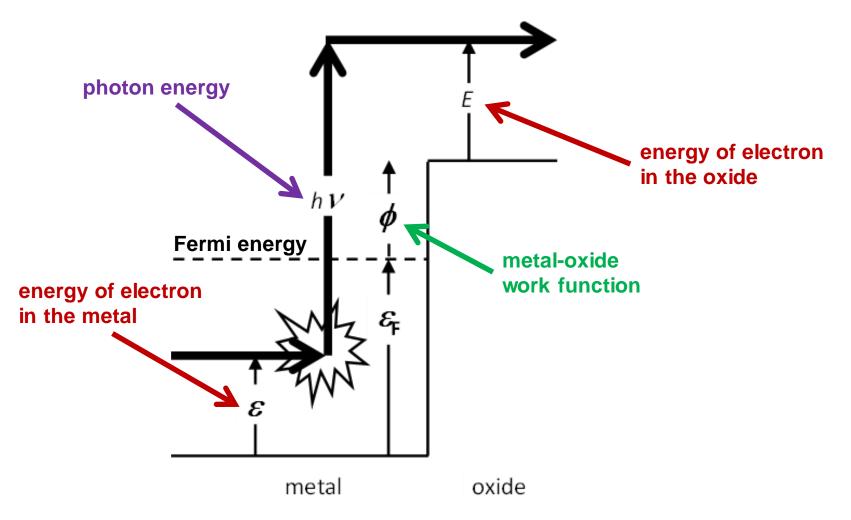


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Excitation and emission of electron into the oxide





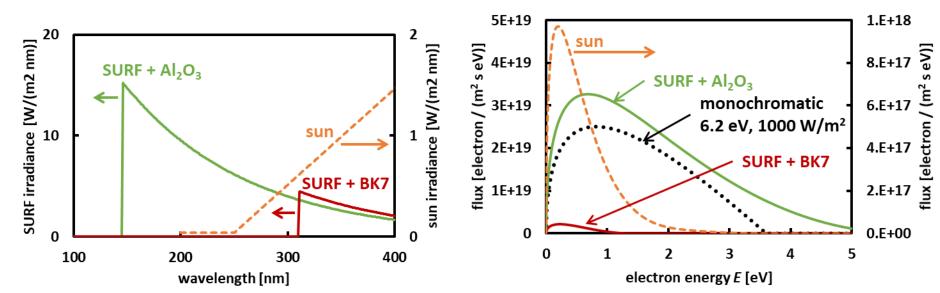
Excitation and emission of electron into the oxide

UV source	UV intensity $I_0(0)$	electron flux J_{e0}	mean energy PEP
	[J m ⁻² s ⁻¹]	[electron m ⁻² s ⁻¹]	[eV]
sun	$2.55 imes 10^2$	$8.1 imes10^{17}$	0.59
SURF SiO ₂	$1.55 imes10^4$	$6.5 imes 10^{19}$	1.40
SURF Al ₂ O ₃	$1.51 imes10^4$	$8.5 imes10^{19}$	1.66
hv = 6.2 eV	1.00×10^{3}	$5.9 imes10^{19}$	1.41

The injected electrons have a broad distribution of energies.



electrons

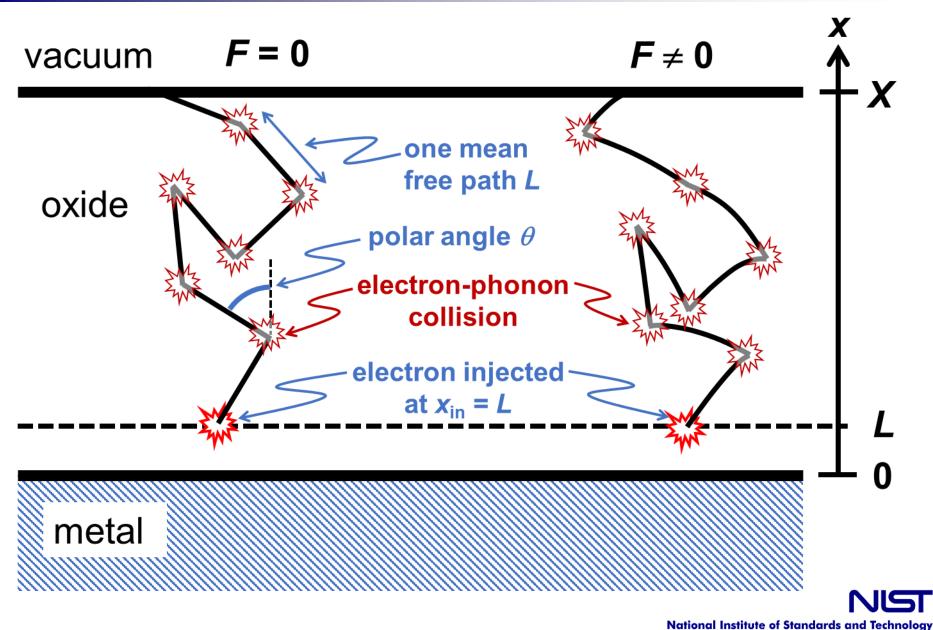


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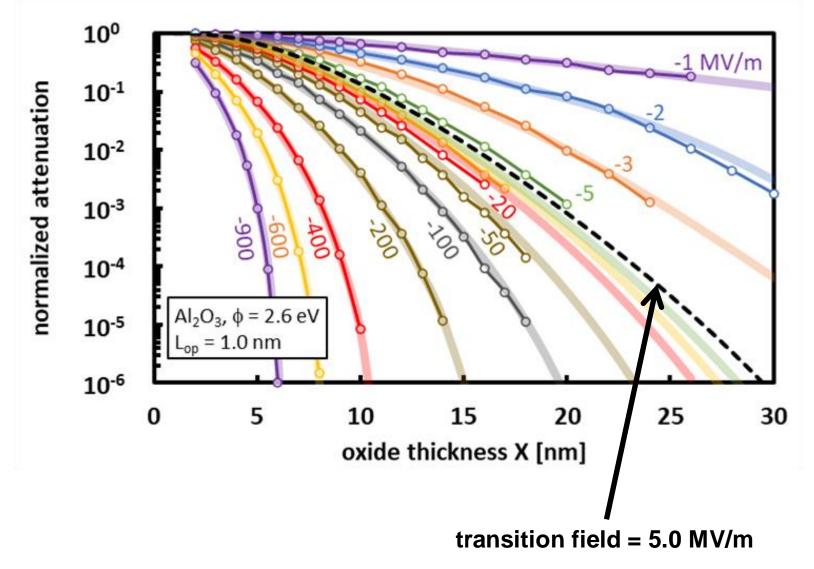


Electron scattering in the oxide



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Electron scattering in the oxide: 2D Monte Carlo



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The five stages of UV-induced oxidation

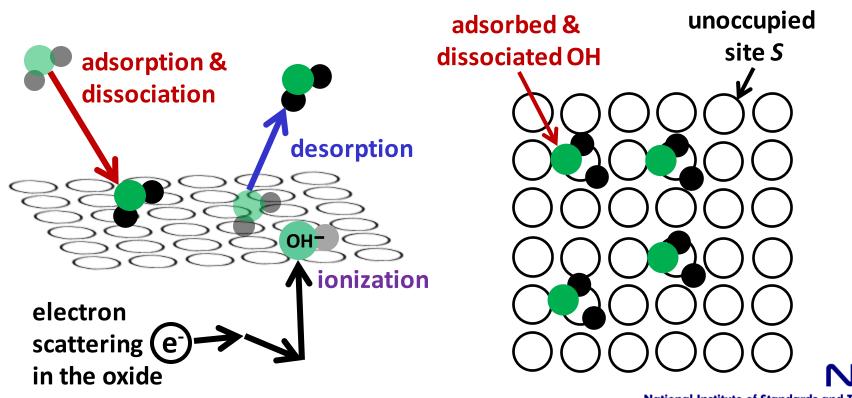
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Surface reactions: adsorption, then ionization

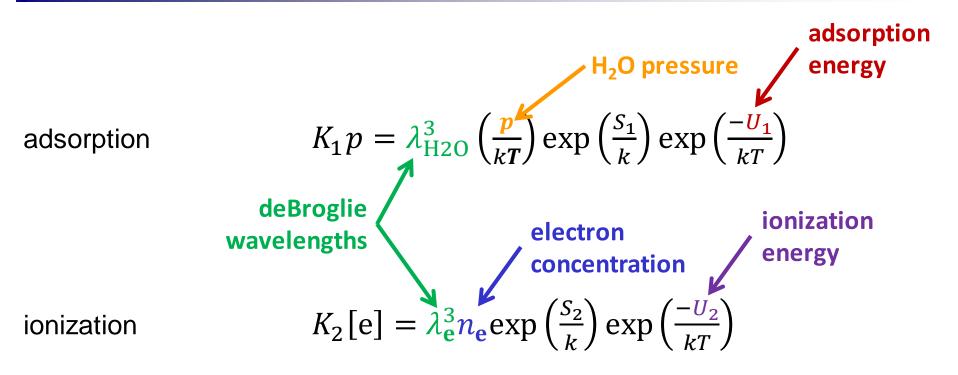
adsorption & dissociation ionization

 $\begin{aligned} & H_2O(gas) + S \rightleftharpoons \mathbf{OH}|S|H & ,K_1 \\ & \mathbf{OH}|S|H + e^- \rightleftharpoons \mathbf{OH}^-|S|H & ,K_2 \end{aligned}$



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Surface reactions: equilibrium constants: K_1, K_2





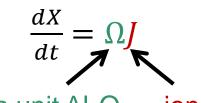
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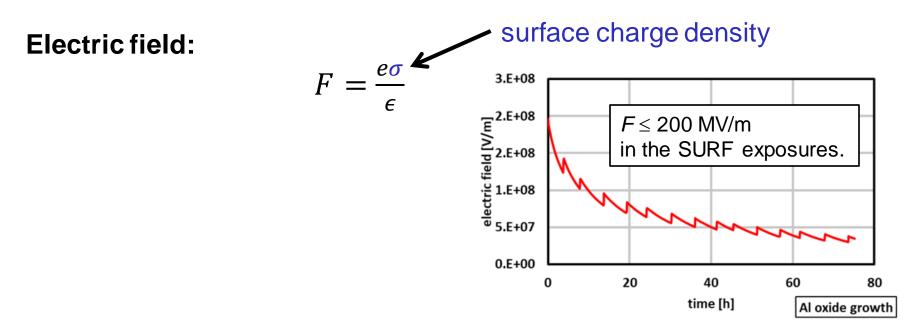


Transport of AI^{+3} : Oxide growth rate dX/dt

Oxide growth rate:



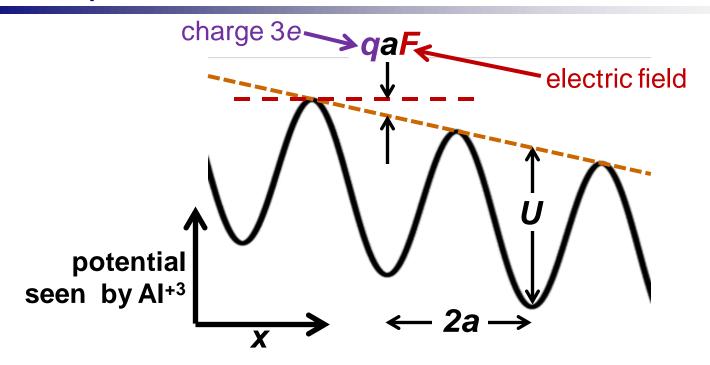
volume of a unit Al_2O_3 ion flux



Use transition state theory to obtain the ion flux in terms of the electric field F.

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Transport of Al⁺³: Transition state theory



If the flux is uniform $(\partial J/\partial x = 0)$ and the field is uniform $(\partial F/\partial x = 0)$, the flux is

$$J = 4av \exp\left(-\frac{U}{kT}\right) \sinh\left(\frac{qaF}{kT}\right) \left[n - \frac{kT}{qF}\frac{dn}{dx}\right]$$

attempt frequency ~*kT/h* density of mobile ions



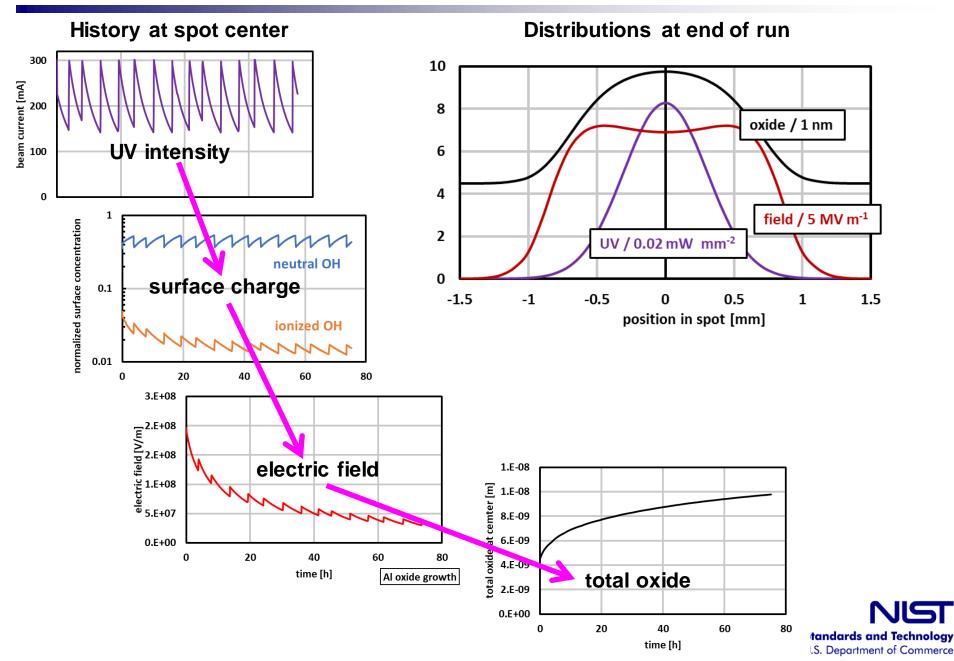
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Luxel 2282-3: Evolution of charge, field, oxide



Comparing the model to the oxide measurements



Modeling strategy

1. Decide what goes in the model.

2. Fit all the SURF exposures by one set of free parameters.

electron mean free path ion barrier hop energy H₂O adsorption energy OH⁻ ionization energy H₂O/photon desorption yield

3. Use literature values of well-known parameters.

Initial oxide thickness Energy of an optical phonon $AI-AI_2O_3$ work function X_0 $E_{\rm phonon}$ ϕ

 U_0

 U_1

 U_2

Y

4. Modify the model's assumptions if there is a problem.

An exposure spot is not well described by the model. A free parameter has an unphysical value.

5. Use the same parameters to describe the SDO degradation.

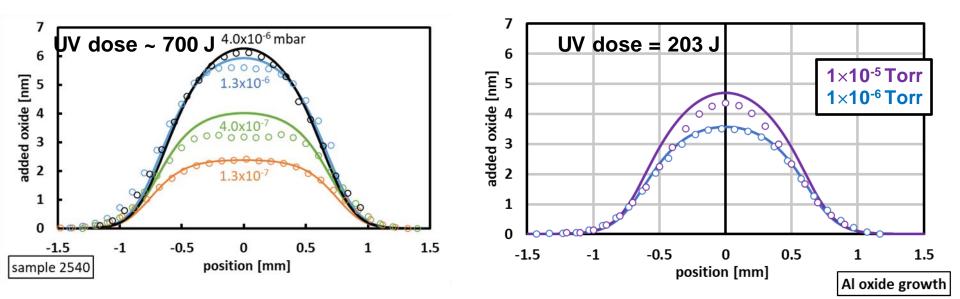
The H_2O pressure is a free parameter.

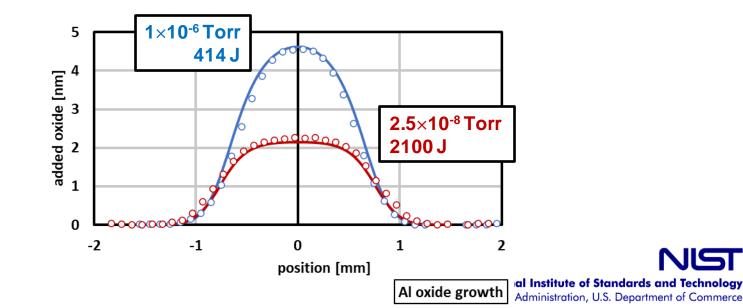


If there is

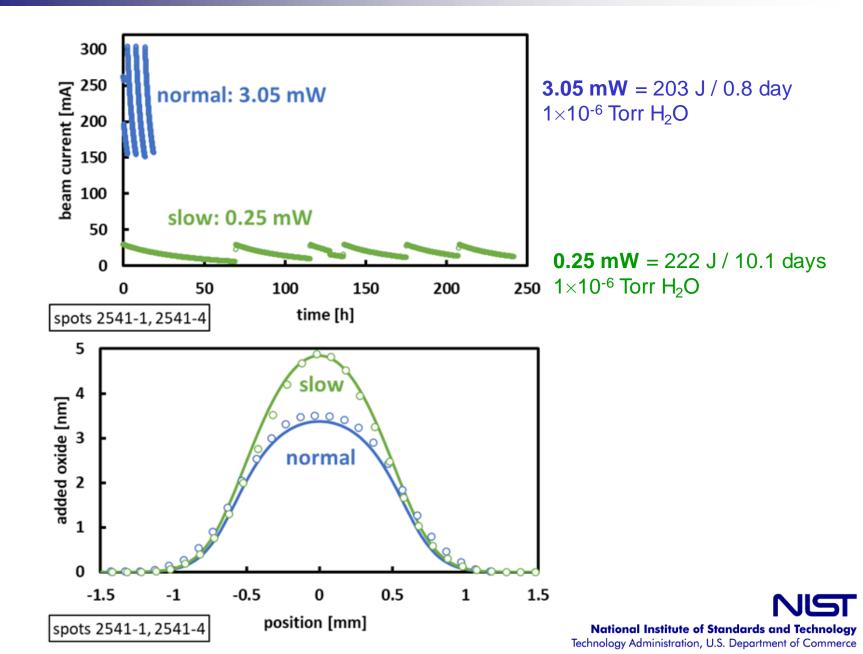
a problem

Vary the H₂O pressure

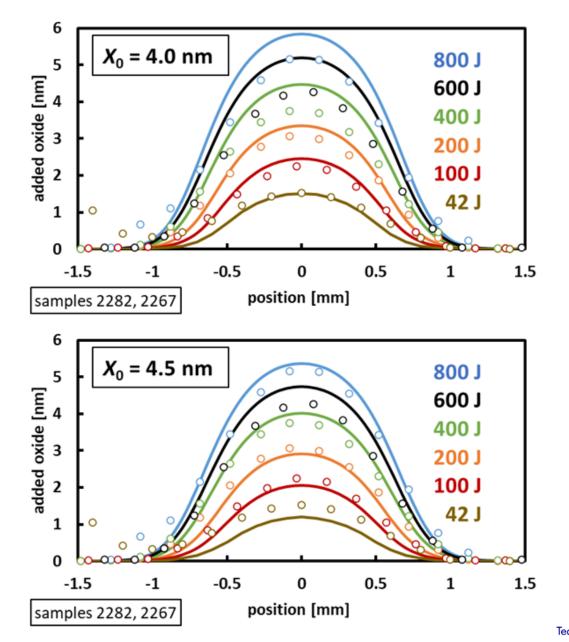




Vary the UV intensity

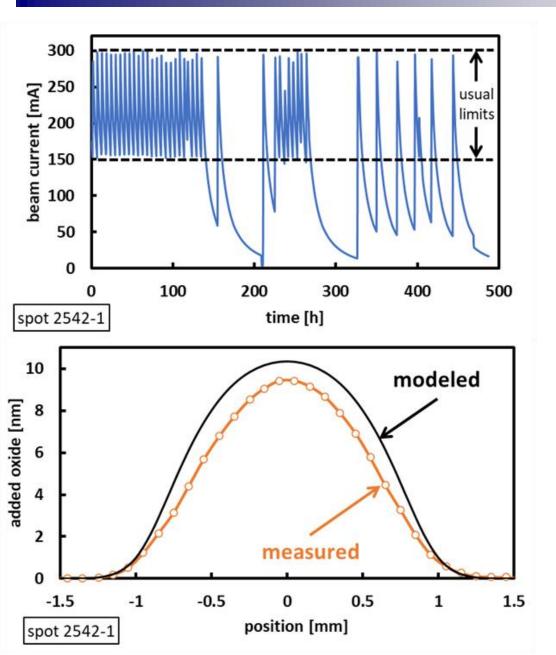


Vary the UV dose





20-day exposure



Mixture of normal and slow runs

2×10⁻⁶ Torr H₂O



Model parameters

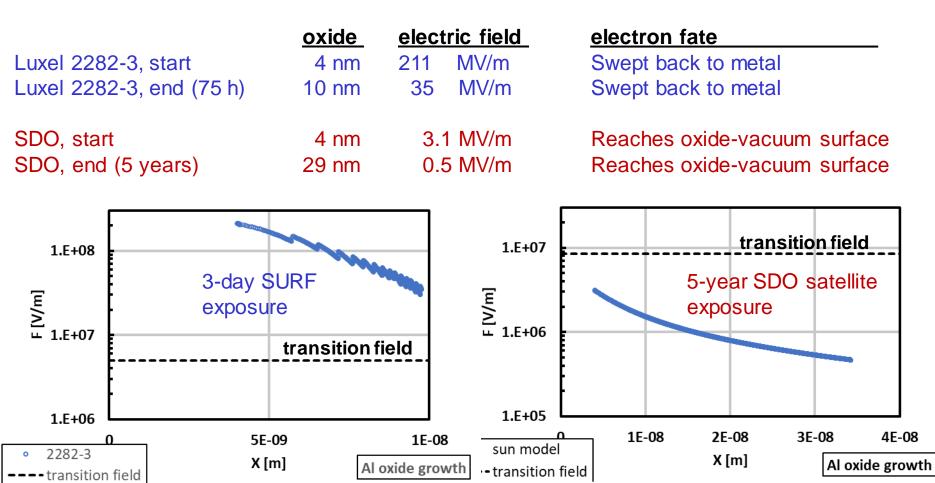
quantity fixed		value used	expected	why expected
initial oxide	X_0	4.0 nm or 4.5 nm	$(4 \pm 1) \text{ nm}$	XPS and XRR of multiple
thickness				surfaces
Al-Al ₂ O ₃ work	ϕ	2.6 eV	$(2.6 \pm 0.6) \text{ eV}$	middle value of literature
function				range
electron-phonon	$E_{\rm op}$	0.05 eV	$(0.05 \pm 0.01) \text{ eV}$	neutron scattering
collision loss				

quantity fitted		value fitted	expected	why expected
electron mean	L	$(1.22 \pm 0.02) \text{ nm}$	$(1.0 \pm 0.2) \text{ nm}$	photoyield of biased
free path				Al-Al ₂ O ₃ -Au sandwich
ion-hop barrier	$+U_0$	$(1.07 \pm 0.02) \text{ eV}$	0.8 eV to 1.6 eV	oxidation at higher T by
energy				exposure to O ₂
H ₂ O adsorption	$-U_1$	$(1.01^{+0.04}_{-0.02}) \text{ eV}$	0.5 eV to 1.8 eV	adsorption on crystal Al ₂ O ₃
energy				
OH ionization	$-U_2$	$(0.68 \pm 0.02) \text{ eV}$	< 1.4 eV	OH electron affinity $-H_2O$
energy				dissociation energy
H_2O / photon	Y	$(4 \pm 1) \times 10^{-4}$	< 18×10 ⁻⁴	desorption from bulk H ₂ O
desorption yield				

What happens to a thermalized electron?

The electric field across the oxide adds a bias to the random walk of a thermalized electron. A strong electric field displaces a thermalized electron between scattering events by more than the mean free path *L*. The electron is ultimately swept back to the metal.

 $F \gg \frac{kT}{eL} = \frac{(0.026 \text{ eV})}{(1 \text{ nm})} = 26 \text{ MV/m}$



Comparing the model to the SDO degradation



- 1. Were the oxide growth rates in the laboratory consistent with those on SDO?
- 2. Was the water vapor pressure on SDO sufficient to produce such oxidation?
- 3. What was the source of the water vapor on SDO?



SDO and laboratory conditions

	SDO	laboratory
radiation spectrum	optical and near-UV	deep-UV and near-UV
H ₂ O pressure	$\sim 10^{-8}$ mbar	3×10^{-8} mbar to 10^{-4} mbar
exposure duration	5 years	1 hour to 20 days

Use the same parameter values that described the SURF oxide growth, with the following exceptions:

- Modify the fixed parameters determined by the incident UV spectral intensity and the resulting photoelectron energy distribution.
- Use the initial oxide thickness X_0 found by fitting the data to the square-root description.

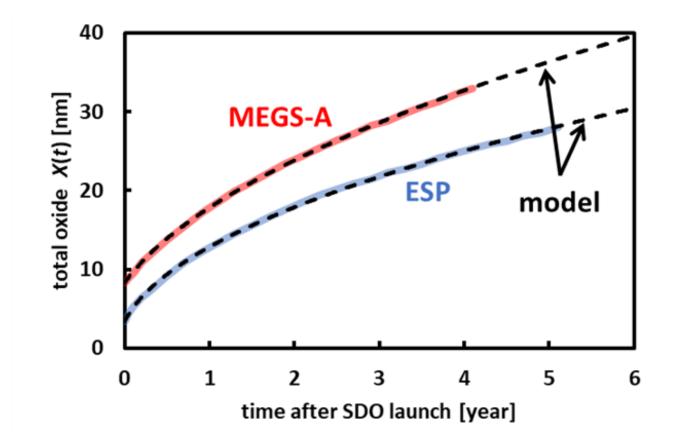
$$X(t) = X_0 \left(1 + \frac{t}{t_0} \right)^{1/2}$$

• Allow the temperature and H_2O pressure to be free parameters.



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Fit results



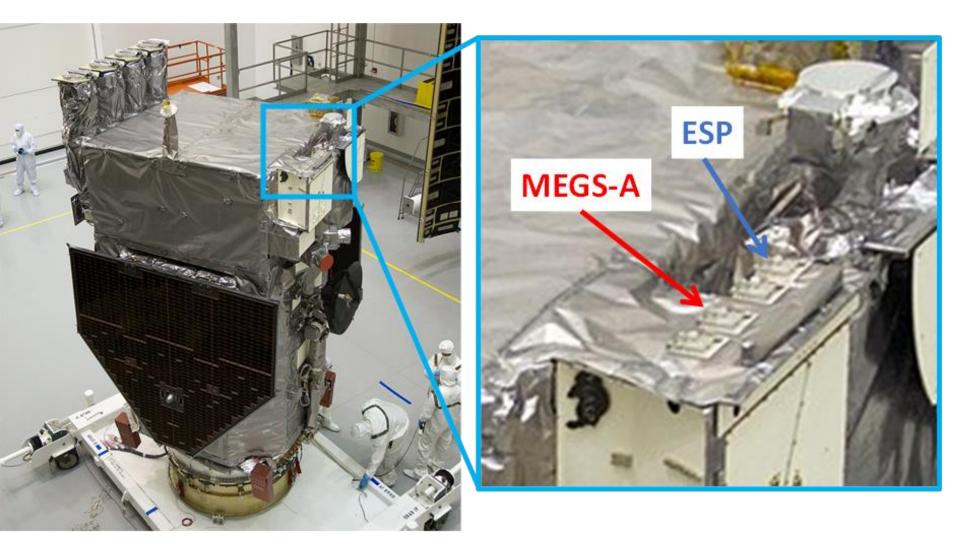
	ESP		MEGS-A	
X_0	3.4	nm	8.3	nm
t_0	0.074	year	0.277	year
Т	306 ± 1	K	314 ± 1	K
$p_{\rm H2O}$	$(0.58 \pm 0.03) \times 10^{-8}$	mbar	$(1.5 \pm 0.10) \times 10^{-8}$	mbar

 mbar
 NIST

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SDO shortly before launch





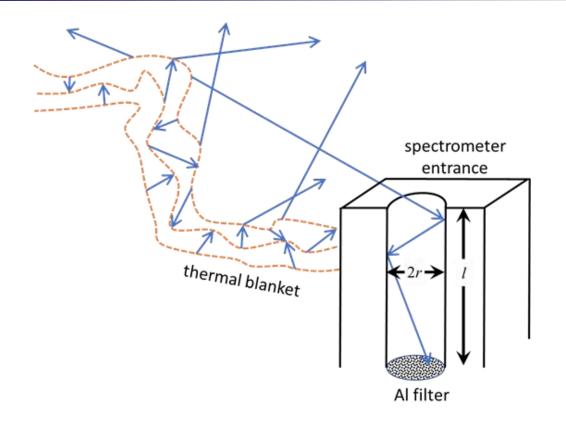
The thermal blanket



At saturation, the blanket can store 0.63 g / m².



The spectrometer can "see" the blanket emission



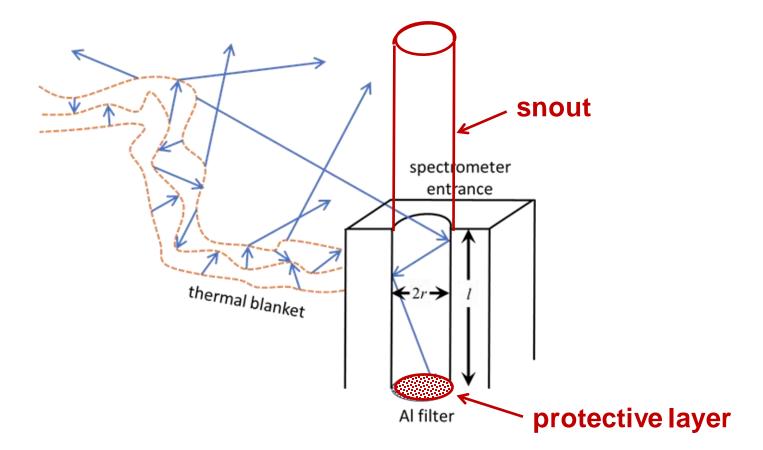
pressure at the filter = (flow out of spectrometer) / (entrance flow conductance)

flow out of spectrometer = flow into spectrometer

If 10% of the entrance view is the blanket, then water released in 5 years from blanket was 0.4 g / m².

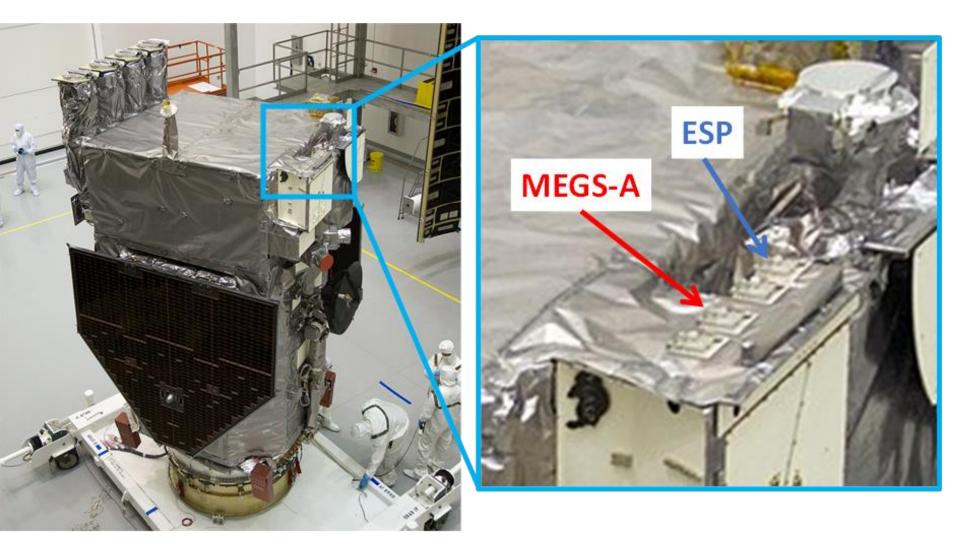


Possible improvements





SDO shortly before launch



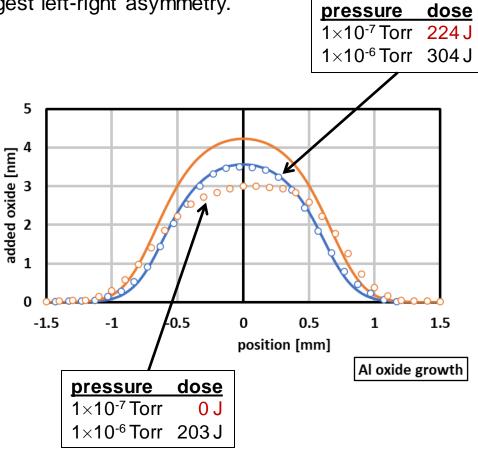


Supplements



2541-3: pressure sequence

- The model overpredicts the oxide growth.
- This spot has the largest left-right asymmetry.



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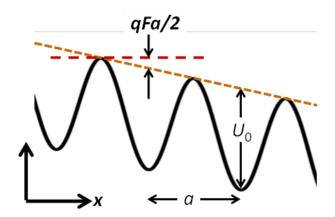
Ion-hopping barrier energy U_0

The Al⁺³ flux through the oxide is limited by the barrier energy U_0 .

The present model found $U_0 = 1.07 \text{ eV}$,

which falls within the broad range of previous studies.

method	temperature [K]	U_0 [eV]
anodization, 180 V	273 - 298	1.30 ± 0.15
O_2 exposure	523 - 723	1.6 ± 0.1
O_2 exposure	600 - 800	1.17 ± 0.05
O_2 exposure	300 - 600	0.9 ± 0.1
	anodization, 180 V O_2 exposure O_2 exposure	anodization, 180 V $273 - 298$ O_2 exposure $523 - 723$ O_2 exposure $600 - 800$



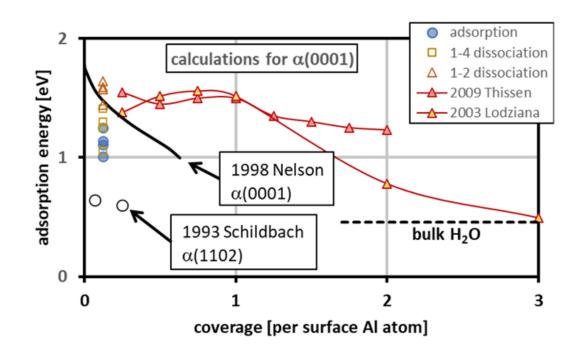


Adsorption energy U_1

An H₂O molecule likely dissociates after desorbing.

<u>surface</u>	- <i>U</i> ₁ [eV]	source
α(0001)	1.0 to 1.8	measured, calculated
α(1102)	0.6	measured
amorphous	broad	?

- The model gives adequate descriptions by fixing $U_1 = -0.98 \text{ eV}$.
- Increasing $-U_1 > 0.97$ eV does not affect the SURF results.
- Increasing $-U_1$ decreases the water partial pressure P_{H2O} that describes the sun results.





Ionization energy U_2

The proposed ionization mechanism is the detachment of an OH group from an AI atom and the subsequent ionization of the OH.

 $AI(OH) + e^- \rightarrow AI + OH^-$

The energy change can be estimated as follows.

 $U_2 = E$ (chemisorbed OH) – E(adsorbed OH) – E(electron affinity of OH) $U_2 \approx E$ (adsorbed H₂O) – E(dissociated H₂O) – E(electron affinity of OH) $U_2 \approx 0.4 \text{ eV} - 1.8 \text{ eV} = -1.4 \text{ eV}$

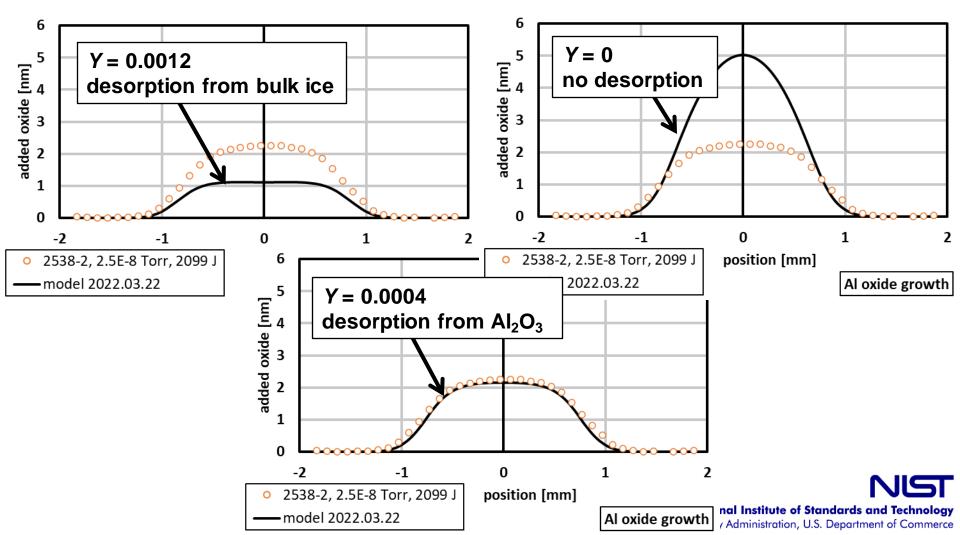
- The negative value means that the reaction is favored energetically.
- If the OH is bound strongly to the AI, the ionization energy will be closer to 0 eV.
- The model fit yielded $U_2 = -0.69$ eV.



Photodesorption: H_2O /photon yield Y is reasonable

This effect was most important for the SURF exposure at the **lowest pressure** of 2.5×10^{-8} Torr. Bulk water $Y = 0.0012 \pm 0.0006$ (Öberg et al. 2009)

< 1 monolayer of H_2O on Al_2O_3 Fitted value in the model Y < 0.0012 \pm 0.0006 (H₂O binds strongly to Al₂O₃) Y = 0.0003



Al⁺³ ion current

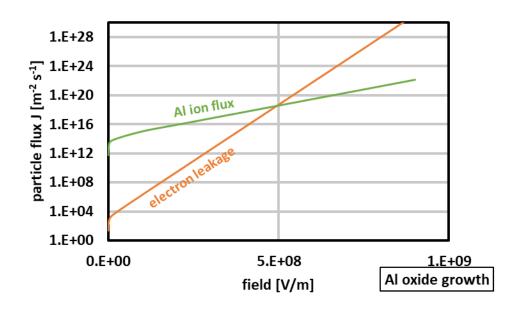
The model assumes that the surface charge, held by OH⁻ ions, is decreased by:

- thermally driven conversion of charged OH- to neutral OH
- electron leakage through the oxide (Fowler-Nordheim tunneling or Poole-Frenkel emission)
- arrival of positively charged Al⁺³ ions

The electron leakage J_{leak} and the Al⁺³ ion flux J_{Al} can both be described by

$$J_{\rm x}(F) = J_{\rm x} \, \sinh\left(\frac{F}{F_{\rm x}}\right)$$

The Al⁺³ ion flux is more important for fields up to 500 MV/m, and the model says that the SURF exposures never created a field larger than 400 MV/m.





Combination of ions

The reaction of cations and anions is assumed to be fast and irreversible.

$$2 \operatorname{Al}^{+3} + 3 \operatorname{OH}^{-} \rightarrow \operatorname{Al}_2\operatorname{O}_3 + 3 \operatorname{H}_2$$

What about the hydrogen?

Hydrogen release has been seen during measurements of adsorption of water of Al oxide. The amount depends on the degree of H_20 dissociation.

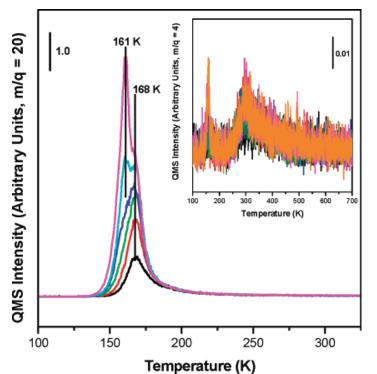


Figure 2. TPD data for various exposure (0.35-2.3 ML) of D_2O (AMU = 20) adsorbed on an ordered, ultrathin $Al_2O_3/NiAl(110)$ film surface. D_2O was deposited at 100 K and the heating rate was 1 K/s. The inset shows D_2 desorption after adsorption of D2O.

2007 [Yi, Szanyi] " D_2O adsorption on an ultrathin alumina film on NiAl(110)"



Excitation and emission of electron into the oxide

1905: Classical electron theory of metals

All of the emitted electrons have nearly the same energy.

 $E = hv - \phi$ metal-oxide work function

~1930: Free electron gas

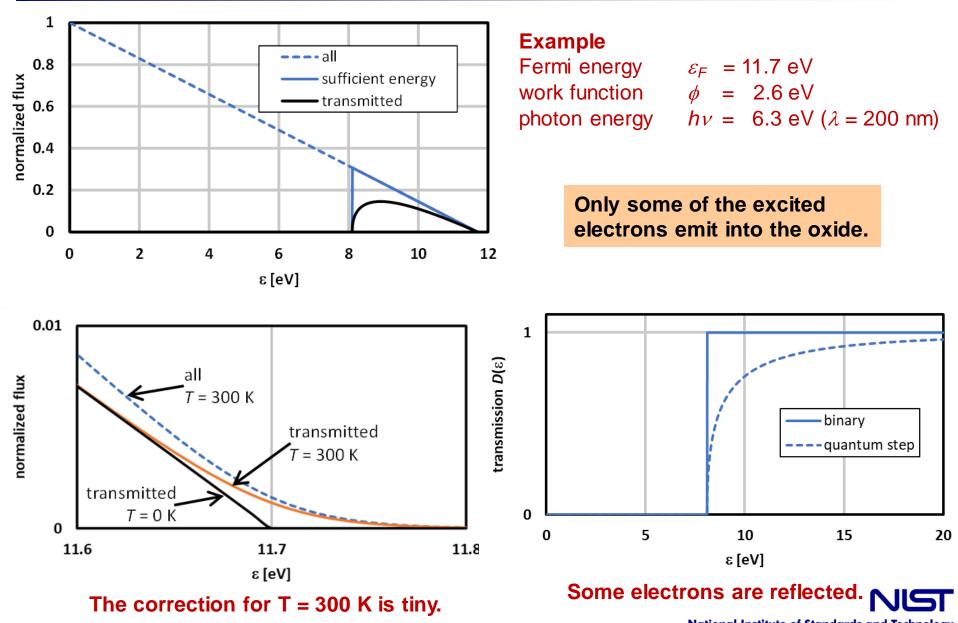
Fermi-Dirac statistics were applied to the free-electron gas by Nordheim (1928), Fowler & Nordheim (1931), DuBridge (1933). The emitted electrons have a broad distribution.

Later: Improvements

Account for scattering of the electrons in the bulk, excitation of plasmons, and the effect of surface states.



Excitation and emission of electron into the oxide

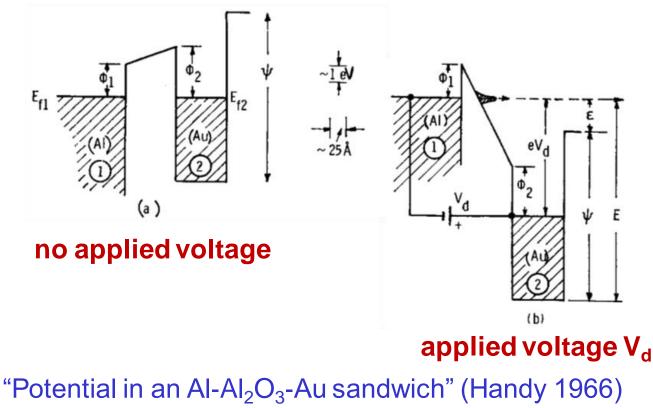


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Electron scattering in the oxide: evidence

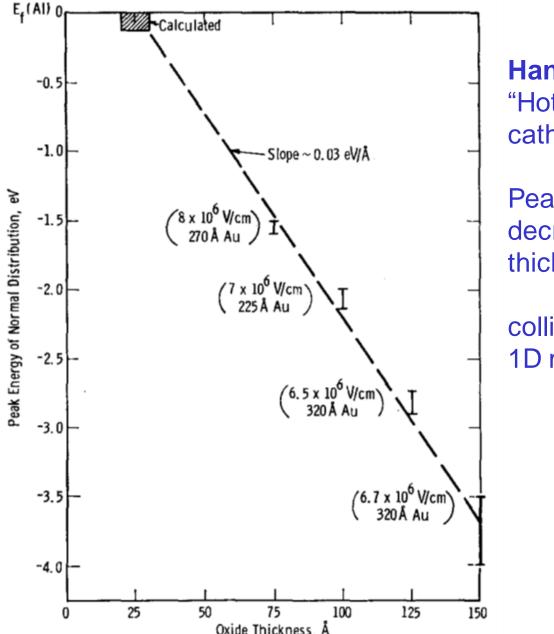
Evidence in the literature for electron scattering in Al₂O₃

- photoelectrons through thin layers of Al₂O₃
- photoemission from metal-oxide-metal (MIM) sandwiches
- I-V curves of MIM sandwiches





Electron scattering in the oxide: evidence



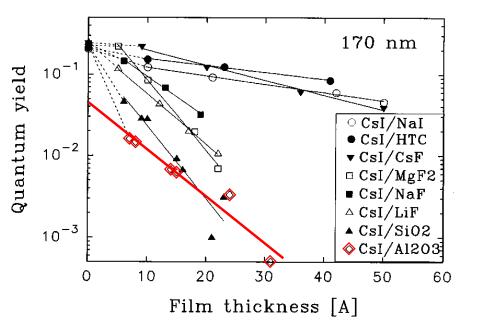
Handy (1968) "Hot electron energy loss in tunnel cathode structures"

Peak energy of emitted electrons decreased linearly with oxide thickness.

collision loss 1D mean free path $E_{\text{phonon}} \equiv 0.1 \text{ eV}$ L = 0.4 nm



Electron scattering in the oxide: evidence



Buzulutskov, Breskin, & Chechik (1998) "Photoemission through thin dielectric coating films"

Photoemission for various films on Csl substrate.

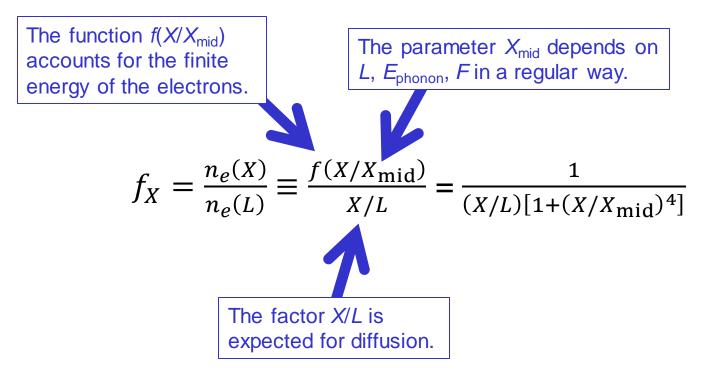
photonshv = 1attenuation length $L_{att} = 1$ 1D mean free pathL = ?

hv = 7..3 eV $L_{\text{att}} = 0.9 \text{ nm}$ L = ?



Electron scattering in the oxide: simulation

The simulation output was the fraction f_{χ} of electrons that reached the oxidevacuum surface for a given combination of mean free path *L*, collision loss E_{phonon} , electric field *F*. The outputs could be represented by the simple empirical function f_{χ} .





Surface reactions: p_{H2O} + [e] \rightarrow surface charge

 $[Z] \equiv$ surface concentration of species Z

equilibrium constant

equilibrium constant

concentration of all sites

 $K_{1} = \frac{[OH|S|H]}{[S]p} H_{2}O \text{ pressure}$ $K_{2} = \frac{[OH^{-}|S|H]}{[OH|S|H][e]} \text{ electron concentration}$

 $M = [S] + [OH|S|H] + [OH^{-}|S|H]$

concentration of open sites $[S] = M(1 + K_1 p + K_1 p K_2 e])^{-1}$

concentration of charged sites $\sigma = [OH^{-}|S|H] = K_2[e][H_2O|S|] = K_2[e]K_1p[S]$

Combine the above to obtain the fraction of sites that are charged:

 $\frac{\text{charged sites}}{\text{all sites}} = \frac{\sigma}{M} = \frac{K_1 p K_2[e]}{1 + K_1 p + K_1 p K_2[e]}$



Transport of Al⁺³: Two approximations

lon flux:

$$J = 4a\nu \exp\left(-\frac{U}{kT}\right) \sinh\left(\frac{qaF}{kT}\right) \left[n - \frac{kT}{qF}\frac{dn}{dx}\right]$$

1. Small electric field F:

$$J = 4a\nu \exp\left(-\frac{U}{kT}\right) \left(\frac{qaF}{kT}\right) \left[n - \frac{kT}{qF}\frac{dn}{dx}\right]$$

$$J = \mu Fn - D \frac{dn}{dx}$$

electric mobility diffusivity

2. Negligible diffusion:

$$J = \mu F n$$

where

$$\mu = \frac{4qa^2\nu}{kT} \exp\left(-\frac{U}{kT}\right)$$



Electron flux attenuation depends on electric field

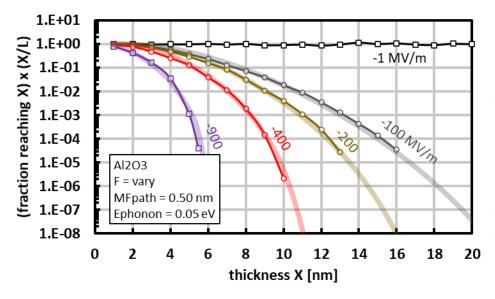
If the electric field is weak:

Each electron injected into the oxide does a random walk until it reaches either the metal or the vacuum surface. The resulting attenuation is described by diffusion, and the fraction that reaches the oxide-vacuum surface at position X is simply L/X, where L is the electron mean free path.

If the electric field is strong:

Each electron does a random walk until it loses all its energy to collisions to optical phonons. If it has not yet reached the vacuum surface, the resulting thermalized electron is swept back to the metal. The fraction that reaches the oxide-vacuum surface depends on the field and oxide thickness. A "strong" field F is one for which

$$F > \frac{kT}{eL} = \frac{(0.026 \text{ eV})}{(\sim 1 \text{ nm})} = 26 \text{ MV/m}$$



Monte Carlo calculations of the electron flux attenuation for electric fields ranging from -100 MV m⁻¹ to -900 MV m⁻¹. The description of the calculations is overlaid on four curves. The points for -1 MV m⁻¹ represent scattering in a weak field.

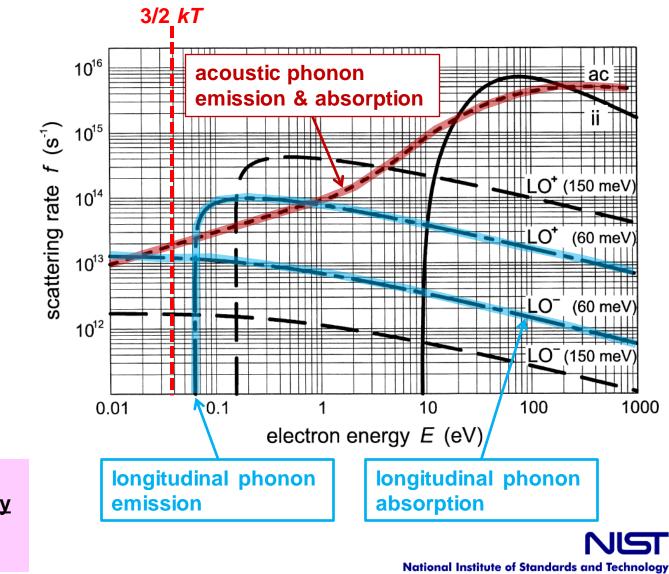
These results are multiplied by X/L so that the result for simple diffusion is 1.



National Institute of Standards and Technology Technology Administration, U.S. Department of Commerce

A thermalized electron sees just acoustic phonons

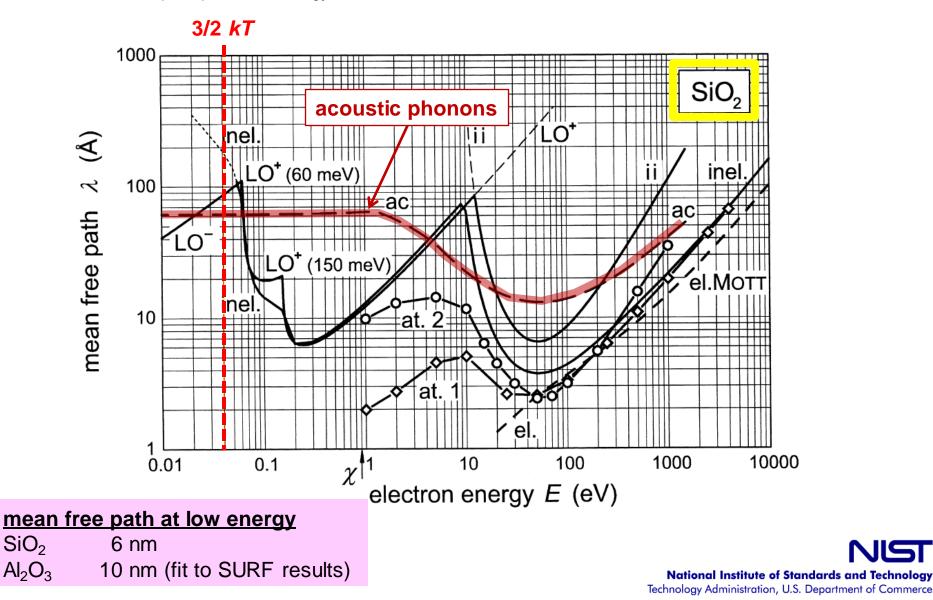
Fitting, Schreiber, Kuhr. von Czarnowski, Journal of Electron Spectroscopy and Related Phenomena **119**, 35–47 (2001). "Attenuation and escape depths of low-energy electron emission"



Technology Administration, U.S. Department of Commerce

A thermalized electron has a long mean free path

Fitting, Schreiber, Kuhr. von Czarnowski, Journal of Electron Spectroscopy and Related Phenomena **119**, 35–47 (2001). "Attenuation and escape depths of low-energy electron emission"



Al⁺³ ion current

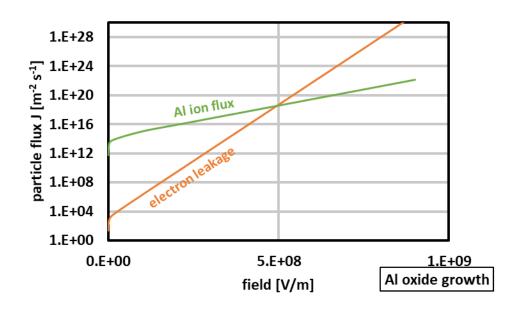
The model assumes that the surface charge, held by OH⁻ ions, is decreased by:

- thermally driven conversion of charged OH- to neutral OH
- electron leakage through the oxide (Fowler-Nordheim tunneling or Poole-Frenkel emission)
- arrival of positively charged Al⁺³ ions

The electron leakage J_{leak} and the Al⁺³ ion flux J_{Al} can both be described by

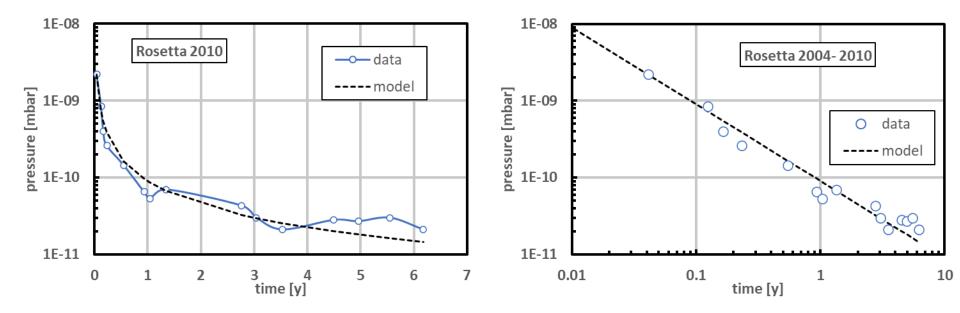
$$J_{\rm x}(F) = J_{\rm x} \, \sinh\left(\frac{F}{F_{\rm x}}\right)$$

The Al⁺³ ion flux is more important for fields up to 500 MV/m, and the model says that the SURF exposures never created a field larger than 400 MV/m.





Enough water outgassing to cause oxidation



The comet probe Rosetta is an example of long-lived outgassing:

- The pressure measured was likely water.
- The pressure decayed slowly, as 1/t.
- The pressure after 6 years was <u>2×10⁻¹¹ mbar</u>.

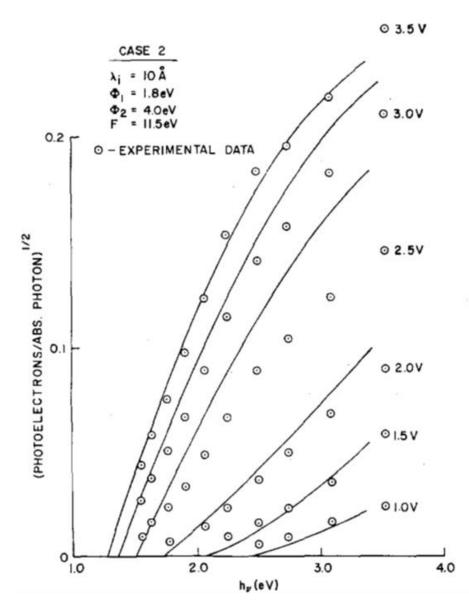
The initial degradation seen on the SDO satellite:

- Corresponds to an oxide growth rate of 13 nm/year.
- This requires an H_2O pressure of at least <u>6×10⁻¹² mbar</u>.



National Institute of Standards and Technology Technology Administration, U.S. Department of Commerce

Electron scattering in the oxide: Literature



Schuermeyer, Young, and Blasingame (1968) "Photovoltage measurements on an Al-Al2O3-Al thin-film sandwich"

Scattering model fit to measured photocurrent as a function of photon energy and bias voltage.

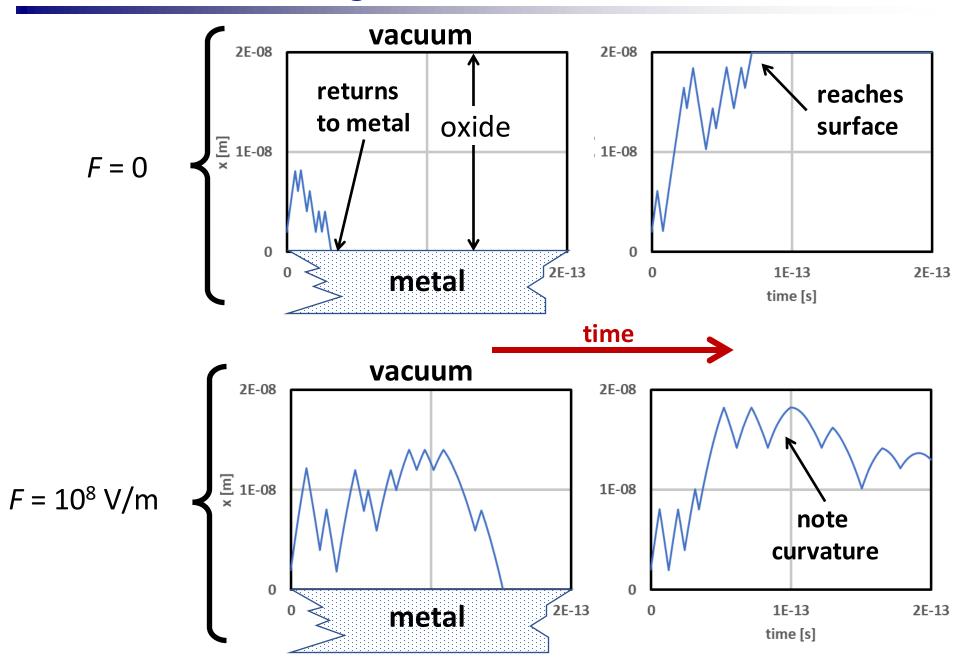
photons collision loss 1.5 eV < hv < 3.5 eV $E_{\text{phonon}} \equiv 0.1 \text{ eV}$

mean free path

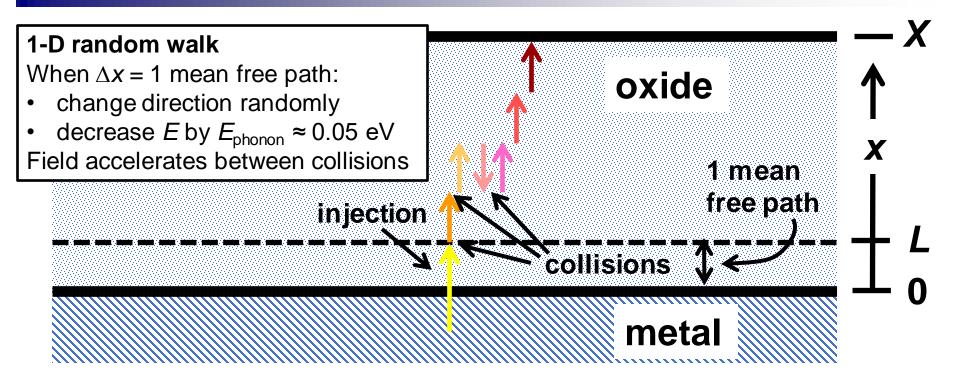
 $L = 1.0 \pm 0.2$ nm



Electron scattering in the oxide: Monte Carlo



Electron scattering in the oxide: 1D Monte Carlo



 $f_{\rm X}$

simulation inputs

X oxide thickness

- 1D mean free path
- $E_{\rm phonon}$ energy loss per collision
- *F* electric field in the oxide
- $\phi_{\rm oxide-vac}$ oxide-vacuum work function
- N(E) energy distribution of injected electrons
- *n*_{max} number of random electron trajectories

simulation output

fraction of electrons that reach x = X



Combination of Al⁺³ with OH⁻

Net reaction $2 \text{ Al}^{+3} + 3 \text{ H}_2 \text{ 0} + 6 \text{ e}^- \rightarrow \text{Al}_2 \text{ 0}_3 + 3 \text{ H}_2$

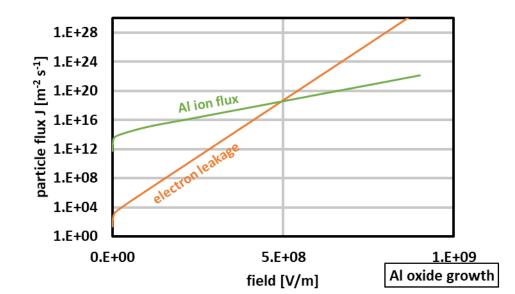
The density of surface charge is decreased by:

- Thermally driven conversion of charged OH- to neutral OH.
- Electron leakage through the oxide (Fowler-Nordheim tunneling or Poole-Frenkel emission).
- Arrival of positively charged Al⁺³ ions.

The electron leakage J_{leak} and the Al⁺³ ion flux J_{Al} can both be described by

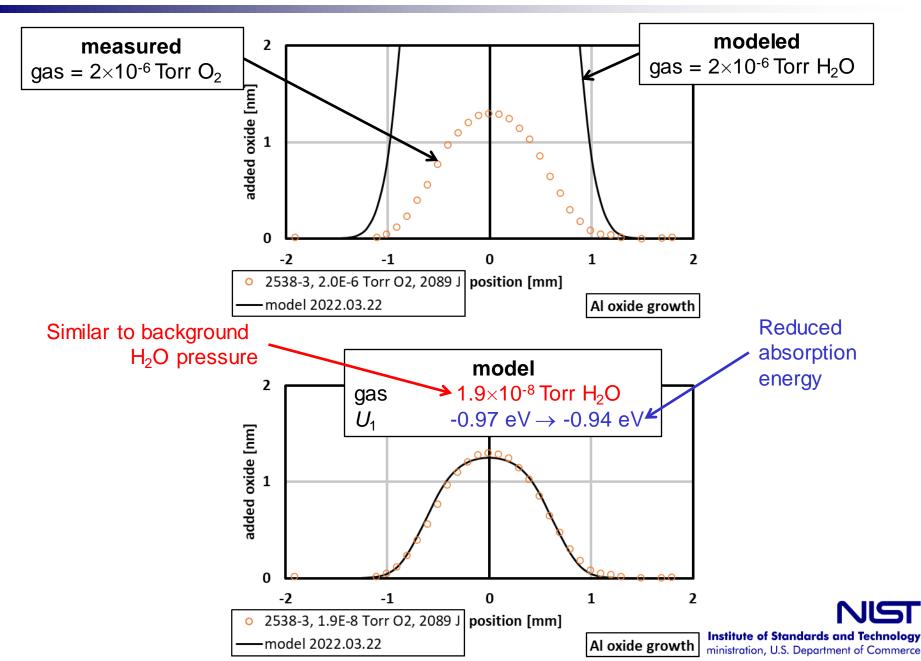
$$J_{\rm x}(F) = J_{\rm x}\,\sinh\left(\frac{F}{F_{\rm x}}\right)$$

Electron leakage was negligible for the SURF exposures because F < 300 MV/m.



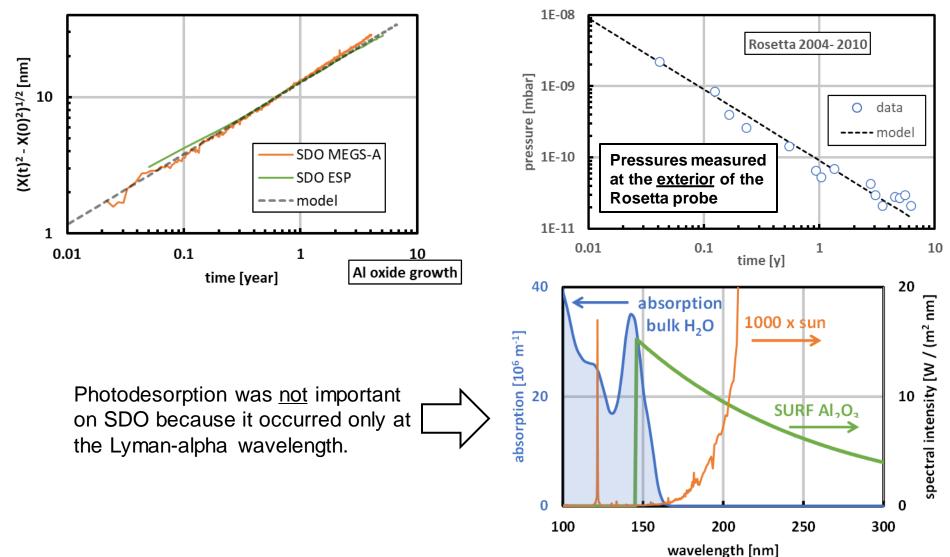


2538-3: H_2O is a better oxidant than O_2

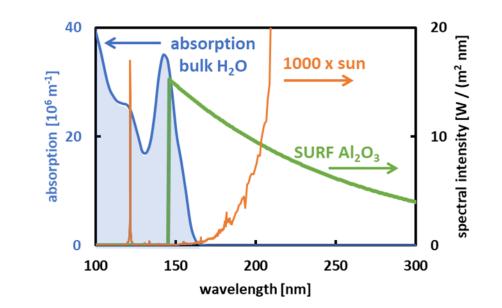


SDO oxide growth

- The model agrees with the SDO data if one sets $P_{H2O} = 2.5 \times 10^{-9}$ mbar.
- This value seems reasonable, but was the outgassing pressure really constant inside SDO?
- Increasing absorption energy U_1 decreases P_{H2O} . SURF results are insensitive to $-U_1 > 0.97$ eV.



SDO oxide growth



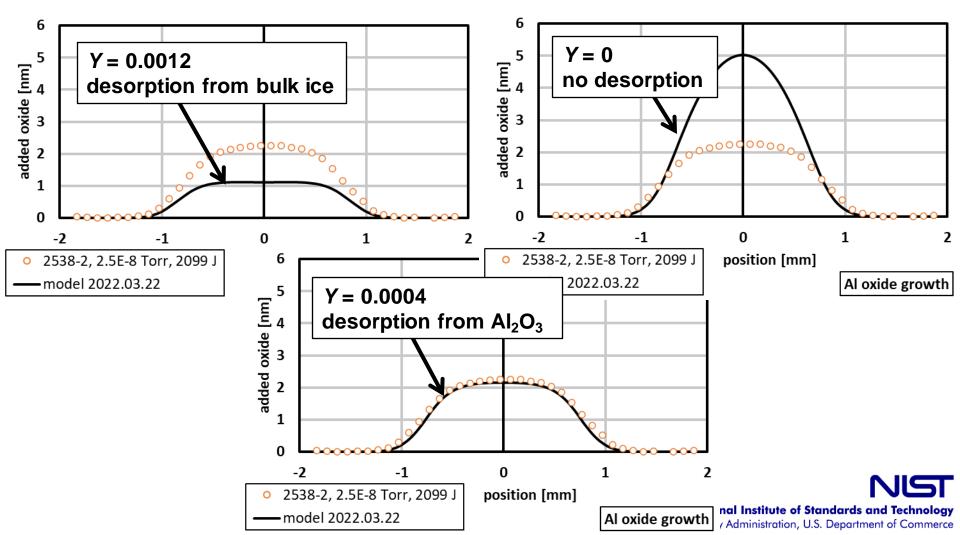
Photodesorption was <u>not</u> important on SDO because it occurred only at the Lyman-alpha wavelength.



Photodesorption: H_2O /photon yield Y is reasonable

This effect was most important for the SURF exposure at the **lowest pressure** of 2.5×10^{-8} Torr. Bulk water $Y = 0.0012 \pm 0.0006$ (Öberg et al. 2009)

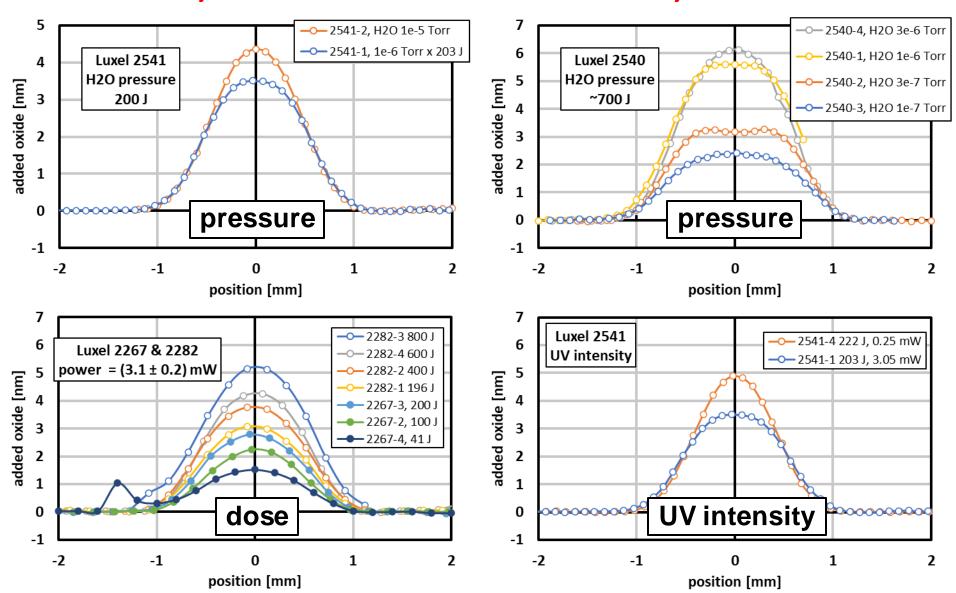
< 1 monolayer of H_2O on Al_2O_3 Fitted value in the model Y < 0.0012 \pm 0.0006 (H₂O binds strongly to Al₂O₃) Y = 0.0003



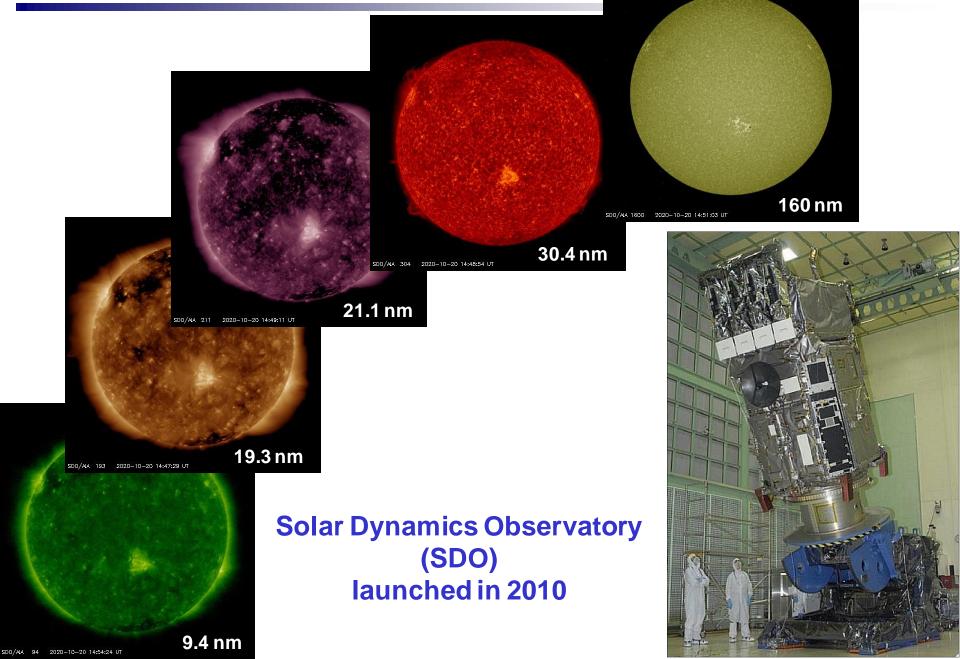
Variations of pressure, dose, and UV intensity

just the data

just the data



Motivation: Observing the sun



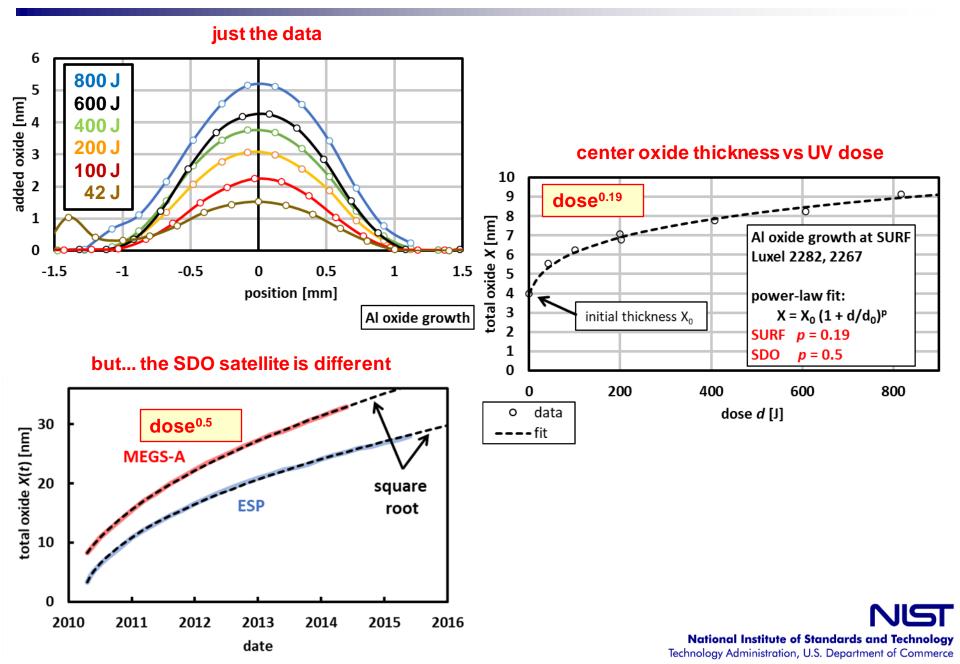
Model parameters

free parameters		value	expected		why expected
electron MF path	L	1.02	1.0 ± 0.2	nm	Schuermeyer (1968)
ion barrier hop energy	U_0	1.07	0.8 to 1.6	eV	literature
H ₂ O adsorption	<i>-U</i> ₁	0.97	0.5 to 1.8	eV	crystal surface adsorption
OH ionization	- <i>U</i> ₂	0.68	< 1.4	eV	OH electron affinity
H ₂ O / photon desorption yield	Y	4×10 ⁻⁴	< 30×10 ⁻⁴		desorption from bulk H ₂ O

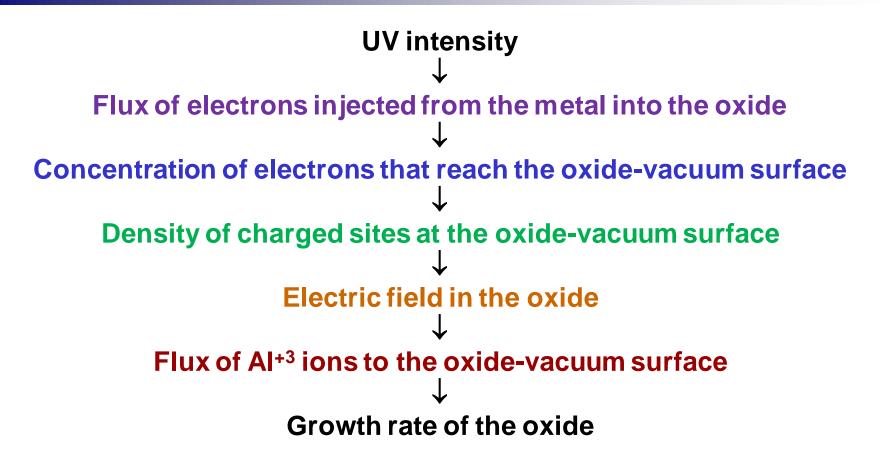
fixed parameters		value	W	hy expected
initial thickness	X_0	4.	nm N	IIST XPS & EDS, literature
phonon collision loss	$E_{\rm phonon}$	0.05	eV n	eutron scattering



Luxel 2282,2267: thickness vs dose



Steps in the model





Approximations in the model

One photon injects, at most, one primary photoelectron and no secondaries.

An electron-phonon collision occurs after the electron has traveled exactly one mean free path.

There is no space charge in the oxide.

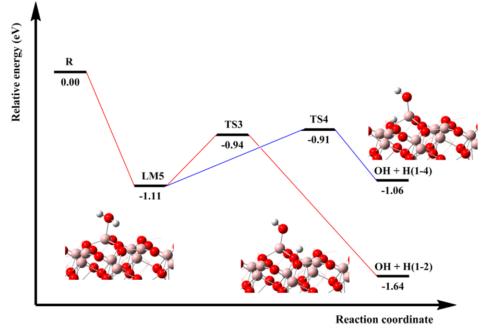
The H₂O adsorption sites at the oxide-vacuum surface have a single energy, not a continuous distribution.

Except for the final reaction of Al⁺³ and OH⁻ ions, the chemical reactions at the oxidevacuum surface are in equilibrium.

The oxide growth rate depends only on oxide thickness, H_2O pressure, and UV intensity, and not the history of these quantities.



Surface reactions: energy of adsorption U_1

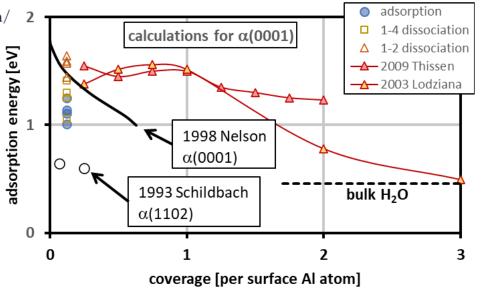


Use the same range measured on α -Al₂O₃(0001) by Nelson et al.

 $U_1 = -(1.4 \pm 0.4) \,\mathrm{eV}$

Figure 8. Schematic potential energy profiles for H_2O adsorption/ dissociation on the Al, O-terminated α -Al₂O₃(0001) surface.

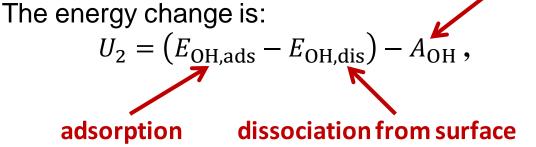
2016 [Lu, Wu, Chen] H_2O adsorption-dissociation and H_2 generation by the reaction of H_2O with AI_2O_3 materials: A first-principles investigation



Surface reactions: energy of ionization U_2

Ionization and detachment of a hydroxyl group from an aluminum atom at the surface: $Al(OH) + e^- \rightarrow Al + OH^-$

electron affinity



Approximate the energy change for OH by that for H₂O: $E_{OH,ads} - E_{OH,dis} \approx E_{H2O,ads} - E_{H2O,dis} \cong 0.4 \text{ eV}$

The energy change is then:

 $U_2 \approx 0.4 \text{ eV} - 1.8 \text{ eV} = -1.4 \text{ eV}$



Electron scattering in the oxide

